

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Lidu Huang, et al.

Serial No.:

10/808,665

Filed:

March 24, 2004

For:

Methods and Apparatuses for Measuring the Refractive Index and Other Optical Properties

of Liquids, Gels and Solids

Art Group Unit: 2877

Examiner:

Unknown

Attorney Docket: 02EK-105598

CERTIFICATE OF MAILING/TRANSMISSION (37 C.F.R. § 1.8A)

I hereby certify that this correspondence is, on the date shown below, being:

(X) deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

> Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450.

() transmitted by facsimile to the Patent and Trademark Office

INFORMATION DISCLOSURE STATEMENT PURSUANT TO 37 C.F.R. §1.56 AND §§1.97-1.98

Commissioner for Patents P.O. Box 1450 Alexandria, CA 22313-1450

Sir:

The citation listed on the enclosed PTO-1449 Form is submitted under 37 C.F.R. §§1.97 and 1.98, and in compliance with the duty of disclosure as defined in 37 C.F.R. §1.56.

The Examiner is requested to make this citation officially of record in the application. This Information Disclosure Statement is being submitted before receipt of the first Office Action for the above-identified application, therefore, pursuant to 37 C.F.R. §1.97, no fee or certification is required.

This Information Disclosure Statement is not to be construed as a representation or admission that any of the listed citations, by itself or in combination with other information, is material to patentability, is, in fact, prior art, or establishes or a prima facie case of unpatentability of any claim in the above-identified application. Additionally, this Information Disclosure Statement is not to be construed as a representation that a further search of the art has been made by Applicants, or that additional information relevant to the examination of this application does not exist unbeknownst to Applicants.

Respectfully submitted,

Registration No. 35,419

September 29, 2004

SHEPPARD MULLIN RICHTER & HAMPTON LLP Four Embarcadero Center, 17th Floor San Francisco, CA 94111-4106 Telephone (415) 434-9100 Facsimile (415) 434-3947

EODM											
FORM PTO-1449 (Modified)					ATTY. DOCKET N	ATTY. DOCKET NO.		SERIAL NO.			
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT(S)' INFORMATION DISCLOSURE STATEMENT					0211 100000	02EK-105598			10/808,665		
OT 0 1 2004					APPLICANT: Lidu Huang, et al.						
					FILING DATE: March 24, 2004				GROUP ART UNIT: 2877		
•	Ē	ESIGNATION		II S DA	ATENT DOCUMENTS						
EXAM'R INITIAL	NOL D	DOCUMENT NUMBER		ATE	NAME	Clas	is	Subclass	Filing Date If Appropriate		
	Α										
	Α										
	Α										
				FOREIGN	PATENT DOCUMENTS	6					
EXAM'R		DOCUMENT NUMBER		DATE	COUNTRY	CLA	SS	Subclass	TRANSI	_AT'N	
INITIAL	В								yes	no	
	В										
	<u> </u>			<u> </u>							
		OTHER A	.RT (I	include Aut	hor, Title, Date, Pertin	ent Page	s. E	tc.)			
	T		. Hua	ang, S. Aoki	, M. G. Lee and K. Yoko				icrolens		
	C7	arrays in silica-			lightwave circuit technors, vol 2, no. 4, pp. 309	ology", Jo	urna			/ ,	
	C7	arrays in silica- Microfabricatio Metricon Corp.	n, & I , "Mo	Microsysten odel 2010 Pr		ology", Jo -318, 200 Notes N	ourna 03 1easi	I of Microlit	hography		
		arrays in silica- Microfabricatio Metricon Corp. Free-Standing Brother Gregor	n, & I , "Mo Polyr y Inv	Microsysten del 2010 Pr mer Films," estigates, "I	ns, vol 2, no. 4, pp. 309	ology", Jo -318, 200 Notes M i6.htm, 6	ourna 03 1easi 5/29/2	I of Microlith uring Index 2004	hography		
	C8	arrays in silica- Microfabricatio Metricon Corp. Free-Standing Brother Gregor	n, & I , "Mo Polyr y Inv	Microsysten del 2010 Pr mer Films," estigates, "I	ns, vol 2, no. 4, pp. 309 ism Coupler Application www.metricon.com/appl Measuring Refractive Inc	ology", Jo -318, 200 Notes M i6.htm, 6	ourna 03 1easi 5/29/2	I of Microlith uring Index 2004	hography		
	C8	arrays in silica- Microfabricatio Metricon Corp. Free-Standing Brother Gregor	n, & I , "Mo Polyr y Inv	Microsysten del 2010 Pr mer Films," estigates, "I	ns, vol 2, no. 4, pp. 309 ism Coupler Application www.metricon.com/appl Measuring Refractive Inc	ology", Jo -318, 200 Notes M i6.htm, 6	ourna 03 1easi 5/29/2	I of Microlith uring Index 2004	hography		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant(s).

FORM PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT(S)' INFORMATION DISCLOSURE STATEMENT E Column Statement Statem					ATTY. DOCKET NO.		SERIAL NO.				
					02EK-105598			10/808,665			
						APPLICANT: Lidu Huang, et al.					
						FILING DATE: March 24, 2004			GROUP ART UNIT: 2877		
# PADEN	NCE DE	ESIGNATION DOCUMENT		U.S. P	ATF	ENT DOCUMENTS					
EXAM'R INITIAL		DOCUMENT NUMBER				NAME	Clas	S	Subclass	Filing Date If Appropriat	
	A1	6,504,966	01/07/200		Kato et al.		385		16		
	A2										
	A3										
	A4										
			F	FOREIGN	N PA	ATENT DOCUMENTS					
EXAM'R INITIAL		DOCUMENT NUMBER		DATE		COUNTRY	CLA	SS	Subclass	TRANSLAT'N	
	В			<u> </u>						,,,,	
	В										
	<u> </u>	OTHER AI	RT (In	clude A	utho	r, Title, Date, Pertine	nt Page	s, E	tc.)		
	C1		d Opt	ical Circu	uits",	edited by H. M. Presb				n", SPIE	
	C1	"Silica Integrate Milestone Serie T. Fukano and	ed Opt es, vol. I. Yam y a lov	ical Circu MS 125 noguchi, "	uits", , pp. 'Sim	edited by H. M. Presb	y, Secti	ion 2	"Fabricatio	active indices	
		"Silica Integrate Milestone Serie T. Fukano and of multilayers by 1942-1944, 199 G. J. Veldhuis,	ed Optes, vol. I. Yam y a lov 06 L.E. W	ical Circu . MS 125 noguchi, " w-cohere V. van Ve	uits", , pp. 'Sim nce	edited by H. M. Presb 43-149, 1996 ultaneous measureme	ent of th microsc	ickne	"Fabrications and refractors and refractors continued in the continued in	active indices vol. 21, pp.	
	C2	"Silica Integrate Milestone Serie T. Fukano and of multilayers by 1942-1944, 199 G. J. Veldhuis, on waveguide b	ed Optes, vol. I. Yam y a lov 6 L.E. Woend lo	ical Circu. MS 125 noguchi, " w-cohere V. van Ve coss", IEE comi, "Mea	uits", , pp. 'Sim nce een a E J.	edited by H. M. Presb 43-149, 1996 Jultaneous measureme confocal interference a and P. V. Lambeck, "In	ent of the microscontegrates I. 17, pp	ickne ope", d opt	"Fabrications and refractor, Opt. Lett., ical refractor, 1999	active indices vol. 21, pp. ometer based	
	C2	"Silica Integrate Milestone Serie T. Fukano and of multilayers by 1942-1944, 199 G. J. Veldhuis, on waveguide by D. C. Yin and Y temperature rar T. Dennis, E. M	ed Optes, vol. I. Yamy a love B. L.E. Wordend Ich I. Inatonge us I. Gill a	ical Circu. MS 125 noguchi, " w-cohere V. van Ve pss", IEE pmi, "Mea sing interf	uits", pp. 'Sim nce en a E J. asuro feror	edited by H. M. Presb 43-149, 1996 sultaneous measureme confocal interference of and P. V. Lambeck, "In Lightwave Technol., v	ent of the microscontegrated 1. 17, pp ex of Gachnol., ve	ickneope", d optob. 85	"Fabrication sess and refractor, Opt. Lett., ical refractor, 1999 systal over a 5, pp. 221-2 of refractive	active indices vol. 21, pp. ometer based large 228, 2000	

EXAMINER DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant(s).